

Korean International Semiconductor Conference & Exhibition on Manufacturing Technology 2025

## **KISM 2025 BUSAN**

Re:Innovation of Semiconductor Manufacturing for AI Ecosystem

[TuC2] Advanced Metrology & Inspection, Process Diagnostics & Control, and Yield	
Management II	
Session Date	November 11 (Tue.), 2025
<b>Session Time</b>	14:50-16:20
Session Room	Room C (Grand Ballroom 3, 2F)

[TuC2-1] [Invited] 14:50-15:20

## The Future Is Here: Next-Gen Semiconductor Metrology & Inspection

Taeyong Jo, Jinwoo Ahn, Jaewon Lee, Jeonghoi Kim, Hansaem Park, Myungjun Lee, and Sangjin Hyun (Samsung Electronics Co., Ltd., Korea)

[TuC2-2] [Invited] 15:20-15:50

## The Importance and Role of MI in Semiconductor Devices' 3D Era

Byoung-Ho Lee (Hitachi Hightech Corp., Japan)

[TuC2-3] [Invited] 15:50-16:20

## Overlay Metrology for Layer Alignment Accuracy in Device Processing

Nahee Park (KLA Corp., USA)